INTERNATIONAL SEARCH REPORT

International Application No
PCT/NL2004/000522

		1 101	/ NEZ004/ 0003ZZ							
A. CLASSIFICATION OF SUBJECT MATTER I PC 7 G03F7/004 G03F7/039										
According to International Patent Classification (IPC) or to both national classification and IPC B. FIELDS SEARCHED										
	SEARCHED currentation searched (classification system followed by classification	symbols)								
IPC 7	G03F									
Documentat	ion searched other than minimum documentation to the extent that suc	th documents are included in th	e fields searched							
Electronic da	ata base consulted during the international search (name of data base	and, where practical, search to	erms used)							
EPO-In	ternal, WPI Data, PAJ									
C. DOCUMENTS CONSIDERED TO BE RELEVANT										
Category °	Citation of document, with indication, where appropriate, of the relev	ant passages	Relevant to claim No.							
Х	US 2003/031953 A1 (J. HATAKEYAMA	ET AL.)	1-9							
	13 February 2003 (2003-02-13)									
	page 22									
χ.	US 2003/008231 A1 (Y. HARADA ET A	L.)	1-9							
	9 January 2003 (2003-01-09)									
	page 20 - page 21									
Χ	US 6 461 790 B1 (J. HATAKEYAMA ET	AL.)	1-9							
	8 October 2002 (2002-10-08)									
	column 28 - column 30; table 3									
χ	US 2001/038969 A1 (J. HATAKEYAMA)		1-9							
	8 November 2001 (2001-11-08)									
,	page 23 - page 24; table 5									
	·									
										
Furti	her documents are listed in the continuation of box C.	X Patent family members	are listed in annex.							
° Special ca	stegories of cited documents:	T" later document published af	ter the international filing date							
	ent defining the general state of the art which is not lered to be of particular relevance	cited to understand the pri	conflict with the application but nciple or theory underlying the							
1	document but published on or after the international	invention "X" document of particular relev	rance; the claimed invention							
"L" docume	ent which may throw doubts on priority claim(s) or	involve an Inventive step w	el or cannot be considered to then the document is taken alone							
citatio	n or other special reason (as specified)	"Y" document of particular releved to in	volve an inventive step when the							
other	ent referring to an oral disclosure, use, exhibition or means	ments, such combination to the art.	h one or more other such docu- being obvious to a person skilled							
	ent published prior to the international filing date but han the priority date claimed	"&" document member of the sa	ame patent family							
Date of the	actual completion of the international search	Date of mailing of the interr								
17 Navambar 2004			04 03. 2005							
	7 November 2004									
Name and	mailing address of the ISA	Authorized officer								
	European Patent Office, P.B. 5818 Patentlaan 2 NL - 2280 HV Rijswijk Tel. (+31-70) 340-2040, Tx. 31 651 epo nl,	D								
	Fax: (+31-70) 340-3016	Dupart, J	M.							

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International application No. PCT/NL2004/000522

Box II Observations where certain claims were found unsearchable (Continuation of item 2 of first sheet)
This International Search Report has not been established in respect of certain claims under Article 17(2)(a) for the following reasons:
1. Claims Nos.: because they relate to subject matter not required to be searched by this Authority, namely:
Claims Nos.: because they relate to parts of the International Application that do not comply with the prescribed requirements to such an extent that no meaningful International Search can be carried out, specifically:
3. Claims Nos.: because they are dependent claims and are not drafted in accordance with the second and third sentences of Rule 6.4(a).
Box III Observations where unity of invention is lacking (Continuation of item 3 of first sheet)
This International Searching Authority found multiple inventions in this international application, as follows:
see additional sheet
As all required additional search fees were timely paid by the applicant, this International Search Report covers all searchable claims.
2. As all searchable claims could be searched without effort justifying an additional fee, this Authority did not invite payment of any additional fee.
3. As only some of the required additional search fees were timely paid by the applicant, this International Search Report covers only those claims for which fees were paid, specifically claims Nos.:
4. No required additional search fees were timely paid by the applicant. Consequently, this International Search Report is restricted to the invention first mentioned in the claims; it is covered by claims Nos.:
Remark on Protest The additional search fees were accompanied by the applicant's protest. No protest accompanied the payment of additional search fees.

FURTHER INFORMATION CONTINUED FROM PCT/ISA/ 210

This International Searching Authority found multiple (groups of) inventions in this international application, as follows:

1. claims: 1-9

a composition suitable for use at 10-165 nm comprising (a) a polymeric binder, (b) a photoactive compound, (c) a dissolution inhibitor, the dissolution inhibitor comprising at least (i) two aromatic groups, (ii) fluorine, and (iii) a blocked acid group which when unblocked has a pka < 12

2. claims: 10-14

a compound represented by formula 1

3. claim: 15

a process for forming an etched layer in a chip comprising, in order: (A) forming a photoresist layer on a substrate wherein the photoresist layer is prepared from a composition comprising (a) a polymeric binder, (b) a photoactive compound, and (c) a dissolution inhibitor, the dissolution inhibitor comprising at least (i) two aromatic groups, (ii) fluorine, and (iii) a blocked acid group which when unblocked has a pKa < 12; (B) imagewise exposing a photoresist layer to form imaged and non-imaged areas; (C) developing the exposed photoresist layer having imaged and non-imaged areas to form a relief image on the substrate; (D) etching the substrate to a predetermined depth; (E) removing the relief image from the substrate

4. claim: 16

a process for the production of a chip by using immersion lithography, comprising the step of forming a photoresist layer on a substrate, wherein the photoresist layer is prepared from a photoresist composition comprising: (a) a binder; (b) a photoactive component, and (c) a fluor containing compound

INTERNATIONAL SEARCH REPORT

Information on patent family members

International Application No PCT/NL2004/000522

Patent document cited in search report		Publication date	Patent family member(s)		Publication date	
US 2003031953	A1	13-02-2003	JP TW	2003082030 584786		19-03-2003 21-04-2004
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